

Plasma Source License Agreement

This license agreement defines the relationship between Seldon Custom Plasmas of Milpitas and Integrated Process Systems Technology Ltd. of Korea relating to the manufacturing, use, and sales of plasma sources using intellectual property described in United States patents # 5,435,881 APPARATUS FOR PRODUCING PLANAR PLASMA USING VARYING MAGNETIC POLES and 5,944,942 VARYING MULTIPOLE PLASMA SOURCE.

Integrated Process Systems Technology Ltd. desires to continue with rights exclusive to companies headquartered in Korea to manufacture, use, and sell equipment including one or more plasma sources using principles described in these patents, and Seldon Custom Plasmas and John Seldon Ogle, the inventor of the plasma sources described in these patents and the owner of these rights, desires to sell such Korean exclusive rights to Integrated Process Systems Ltd. This document is a restatement of previous agreements signed by officials of Seldon Custom Plasmas and Chung Song Systems Co. Ltd, a previous name of Integrated Process Systems Technology Ltd., and John Seldon Ogle of Seldon Custom Plasmas.

The license agreement is based on a unit license arrangement, where any plasma source using principles described by the patent claims and manufactured, used, or sold by Integrated Process Systems Technology Ltd. will have permanently attached a license label purchased from and authorized by an official of Seldon Custom Plasmas.

License labels authorized by Seldon Custom Plasmas will be made available without limit to either number or time, as long as this agreement is in effect. This agreement will be terminated under any of the following conditions:

- 1) When patent protection under United States patents # 5,435,881 and 5,944,942 expire or are declared completely invalid by the United States Patent Office.
- 2) If Integrated Process Systems Ltd. intentionally manufactures, uses, or sells equipment including a plasma source which does not have a permanently attached license label purchased from Seldon Custom Plasmas and which uses principles described in the claims of these patents.
- 3) By mutual consent between authorized officers of Seldon Custom Plasmas and Integrated Process Systems Ltd.
- 4) If Integrated Process Systems Ltd. intentionally assists any subsidiary or associate organization to manufacture, use, or sell equipment including a plasma source which does not have a permanently attached license label purchased from Seldon Custom Plasmas and which uses principles described in the claims of either of these patents.

5) If no licenses are purchased from Seldon Custom Plasmas by Integrated Process Systems Ltd. for an interval of a year.

The cost of each license label will be \$4000 in United States currency. While this agreement is in effect, Seldon Custom Plasmas personnel will provide additional design support and consulting.

Signed John Seldon Ogle
President
Seldon Custom Plasmas

date February 3, 2004

Signed H. S. CHANG

date Feb 11, '04

President, CEO
Integrated Process Systems Ltd.